

IN THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application.

Claims 1-13. (Cancelled)

14. (Original) A method of manufacturing a semiconductor device, comprising:
  - forming an underlying region including an interlevel insulating film on a semiconductor substrate;
  - forming a bottom electrode film pattern on the underlying region;
  - covering upper and side surfaces of the bottom electrode film pattern with an alumina film;
  - removing a part of the alumina film to expose the upper surface of the bottom electrode film pattern and to leave a part of the alumina film, which is formed on the side surface of the bottom electrode film pattern;
  - forming a dielectric film on the exposed upper surface of the bottom electrode film pattern; and
  - forming a top electrode film on the dielectric film.

15. (Original) The method according to claim 14, wherein forming the dielectric film comprises:

- forming a dielectric film pattern on the bottom electrode film pattern;
- covering upper and side surfaces of the dielectric film pattern with another alumina film; and
- removing a part of said another alumina film to expose the upper surface of the dielectric film pattern and to leave a part of said another alumina film, which is formed on the side surface of the dielectric film pattern.

16. (Original) The method according to claim 14, wherein removing the part of the alumina film is performed using a CMP process.

17. (Original) The method according to claim 14, wherein the dielectric film is a metal oxide film.

18. (Original) A method of manufacturing a semiconductor device, comprising:  
forming an underlying region including an interlevel insulating film on a semiconductor substrate;  
forming a bottom electrode film on the underlying region;  
forming a dielectric film pattern on the bottom electrode film;  
covering upper and side surfaces of the dielectric film pattern with an alumina film;  
removing a part of the alumina film to expose the upper surface of the dielectric film pattern and to leave a part of the alumina film, which is formed on the side surface of the dielectric film pattern; and  
forming a top electrode film on the exposed upper surface of the dielectric film pattern.

19. (Original) The method according to claim 18, wherein removing the part of the alumina film is performed using a CMP process.

20. (Original) The method according to claim 18, wherein the dielectric film is a metal oxide film.